IN THE CLAIMS

1. (Currently Amended) A method of extracting two-dimensional image shapes of submicron structures formed by photolithography on semiconductor wafers, from a two-dimensional array of pixel data, the method comprising the steps of:

using a photolithography process to form a submicron structure on a semiconductor wafer;

forming an electron beam image of said structure on a two-dimensional array of pixels, wherein said image has a shape;

identifying a preliminary, approximate edge of the image shape; identifying a more precise edge of the image shape by

- a) identifying a point along said approximate edge,
- b) obtaining intensity vs. pixel information in along a plurality of scans extending in different directions, through substantially the same said point, in the vicinity of an the edge of the image shape;
 - c) recognizing scans with sufficient contrast as containing edge information;
 - d) subjecting the recognized scans to an edge detection algorithm;
- d) e) detecting a point on the more precise edge location of the image by using said edge detection algorithm; and
- f) repeating steps b), c), d) and e) for different points along the approximate edge to generate a locus of points that define the two-dimensional shape of the image from the detected edge values.

2. (Original) A method according to Claim 1, wherein the edge detection algorithm is a user defined edge detection algorithm that is tailored to the application.

Claim 3 (Cancelled).

- 4. (Previously Presented) A method according to Claim 1, wherein the obtaining step includes the step of obtaining intensity vs. pixel information in at least four directions.
- 5. (Previously Presented) A method according to Claim 1, wherein one of said directions is normal to the approximate edge location.
- 6. (Currently Amended) Apparatus for extracting two-dimensional shape information from an image, of a submicron structure, formed on an array of detectors, comprising:

means for using a photolithography process to form a submicron structure on a semiconductor wafer;

means for forming an election beam image of said structure on a twodimensional array of pixels, wherein said image has a shape;

> means for identifying a preliminary approximate edge of the image shape; means for identifying a more precise edge on the image shape by

- a) identifying a point along said approximate edge,
- b) obtaining intensity vs. detector location information for detectors on a plurality of scans in a plurality of angularly different directions, through substantially said point, in the vicinity of an the edge of the image;

- c) identifying scans having sufficient pixel contrast to provide edge information;
- d) processing identified scans according to an edge detection algorithm to identify a point on the more precise edge of the image; and
- f) e) repeating functions b), c), and d) and e) for different points along the approximate edge to generate a locus of points that define the two-dimensional shape of the structure from the identified edge points.
- 7. (Original) Apparatus according to Claim 6, wherein the edge detection algorithm is a user defined edge detection algorithm that is tailored to the application.

Claim 8 (Cancelled).

- 9. (Previously Presented) Apparatus according to Claim 6, wherein the plurality of directions includes at least four directions.
- 10. (Previously Presented) Apparatus according to Claim 6, wherein one of said directions is normal to an approximate edge location.
- 11. (Currently Amended) A program storage device readable by machine, tangibly embodying a program of instructions executable by the machine to perform method steps for extracting two-dimensional image shapes of submicron structures formed by

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photolithography on semiconductor wafers, from image data on a pixel array, the method steps comprising:

using a photolithography process to form a submicron structure on a semiconductor wafer;

forming an electron beam image of said structure on a two-dimensional array of pixels, wherein said image has a shape;

identifying a preliminary, approximate edge of the image shape; identifying a more precise edge of the image shape by

- a) identifying a point along said approximate edge,
- b) obtaining intensity vs. pixel information along a plurality of scans extending in different directions, through substantially said point, in the vicinity of the edge of the image shape;
 - c) recognizing scans with sufficient contrast as containing edge information;
 - d) subjecting the recognized scans to an edge detection algorithm;
- e) detecting a point on the more precise edge location of the image by using said edge detection algorithm; and
- f) repeating steps b), c), d) and e) for different points along the approximate edge to generate a locus of points that define the two-dimensional shape of the image from the detected edge values.
- 12. (Original) A program storage device according to Claim 11, wherein the edge detection algorithm is a user defined edge detection algorithm that is tailored to the application.

Claim 13 (Cancelled).

- 14. (Previously Presented) A program storage device according to Claim 11, wherein the obtaining step includes the step of obtaining intensity vs. pixel information in at least four directions.
- 15. (Original) A program storage device according to Claim 11, wherein one of the directions is normal to an approximate edge location.
- 16. (Previously Presented) A method according to Claim 1, wherein the plurality of directions are angularly spaced apart about 22½ degrees.
- 17. (Previously Presented) A method according to Claim 1, wherein the plurality of directions are angularly spaced apart about 45 degrees.
- 18. (Previously Presented) Apparatus according to Claim 6, wherein the plurality of directions are angularly spaced apart about 22 ½ degrees.
- 19. (Previously Presented) Apparatus according to Claim 6, wherein the plurality of directions are angularly spaced apart about 45 degrees.
- 20. (Previously Presented) A program storage device according to Claim 11, wherein the plurality of directions are angularly spaced apart about 22 ½ degrees.

21. (Previously Presented) A program storage device according to Claim 11, wherein the plurality of directions are angularly spaced apart about 45 degrees.